

U.S.S.N. 10/050,322

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Tsai et al.

Group Art Unit: 1756

Serial No.: 10/050,322

Examiner: N. M. Barreca

Filed: 01/15/2002

In Response to Office Action

Dated: 04/13/2005

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For: A BI-LAYER PHOTORESIST DRY DEVELOPMENT AND REACTIVE  
ION ETCH METHOD

Attorney Docket No.: 67,200-613

CERTIFICATE OF MAILING OR FACSIMILE TRANSMISSION

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Randy W. Tung

Printed Name

Signature

10/20/05

Date

Please forward all correspondence to  
TUNG & ASSOCIATES  
838 W. Long Lake Road, Suite 120  
Bloomfield Hills, MI 48302

STATEMENT OF COMMON OWNERSHIP PURSUANT TO 35 USC 103(c)

Applicants' attorney of record state that Tsai et al. (6,787,455) and Applicants' instant application were, at the time the invention was made, owned by Taiwan Semiconductor Manufacturing Company. Therefore, Examiners use of Tsai et al. as a reference in a 103(a) rejection appears to be improper under 35 USC §103(C).

Respectfully submitted,

TUNG &amp; ASSOCIATES, PLL

Randy W. Tung

Reg. No. 31,311

Telephone: (248) 540-4040